

OCT 24 2002

In re application of : Mitsusuke Kyogoku, et al.

App. No. : 09/650,122

Filed : August 29, 2000

For : SEALING MECHANISM OF
MULTI-CHAMBER LOAD-
LOCKING DEVICE

Examiner : R. Kackar

Art Unit : 1763

I hereby certify that this correspondence and all marked
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(Date)

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TC 1700

Sir:

Transmitted herewith is an amendment in the above-identified application.

(X) An extension of time to respond for 1 month(s) is hereby requested. \$110 large entity

The fee has been calculated as shown below:

CLAIMS AS FILED					
	CLAIMS REMAINING AFTER AMENDMENT	HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
Total Claims	7	20	= 0 ×	\$18	= \$0
Independent Claims	1	3	= 0 ×	\$84	= \$0
Time Extension Fee					\$110
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT					\$110

(X) Amendment After Final in seven (7) pages

(X) Return prepaid postcard.

(X) A check in the amount of \$110.00 is enclosed.

(X) Please charge any additional fees, including any fees for additional extension of time, or credit overpayment to Deposit Account No. 11-1410.

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Kyogoku et al.) Group Art Unit 1763
Appl. No. : 09/650,122)
Filed : August 29, 2000)
For : SEALING MECHANISM OF)
MULTI-CHAMBER LOAD-)
LOCKING DEVICE)
Examiner : R. Kackar)

AMENDMENT AFTER FINAL

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In response to the Office Action mailed July 22, 2002 (Paper number 6), please amend the above-captioned application as follows:

IN THE CLAIMS:

Please cancel Claims 8 and 10 without prejudice.

Please amend Claim 1 as follows:

1. (Twice amended) A multi-chamber load-locking device for transferring wafers between a first-pressure area and a second-pressure area, said device having an interior divided into (i) an upper chamber and (ii) a lower chamber, both of which are for transferring wafers at the second pressure which is higher than the first pressure, and (iii) an intermediate section located between the upper chamber and the lower chamber, which is for loading/unloading wafers at the first pressure, said device comprising (a) a single divider plate having an upper side and a lower side, both of which are for temporarily supporting wafers, said plate moving reciprocally between an upper position and a lower position; (b) a cylindrical cam structure coaxially connected to said plate, wherein said plate moves between the first position and the

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